REQUEST **FOR** CONTINUED EXAMINATION (RCE) **TRANSMITTAL**

MAIL STOP RCE

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Subsection (b) of 35 U.S.C. § 132, effective on May 29, 2000,

Application Number	10/516,455		
Confirmation Number	2876		
Filing Date	December 3, 2004		
First Named Inventor	Michel PUECH		
Group Art Unit	1792		
Examiner Name	Allan W. OLSEN		
Matter Number	Q84452		
ETCHING WIT	METHOD AND DEVICE FOR SUBSTRATE ETCHING WITH VERY HIGH POWER Sitte DID ICTIVELY COURS ED BLASMA		

	rides for continued examination of an utility or ant application filed on or after June 8, 1995	Title	METHOD AND DEVICE FOR SUBSTRATE ETCHING WITH VERY HIGH POWER INDUCTIVELY COUPLED PLASMA			
This is a Re	quest for Continued Examination (RCE) under 37 (C.F.R. §	1.114 of the above-identified application.			
1. SUBMIS	SSION REQUIRED UNDER 37 C.F.R. § 1.114					
	 a. □ Previously submitted i. □ Please enter and consider the amendment(s)/reply under 37 C.F.R. § 1.116 previously filed on					
	Other Enclosed Amendment/Reply Affidavit(s)/Declaration(s) Information Disclosure Statements (IDS) Petition for Extension of Time Other					
a. □ S	LLANEOUS Suspension of action on the above-identified application of months Other	ation is r	equested under 37 C.F.R. § 1.103(c) for a			
USPTO is a	statutory fee of \$810.00 is being charged to Deposition of the count No. 19-4880. Please also credit any overpayments	es, exce	pt for the Issue Fee and the Publication Fee, to			
	CORRESPONDENC					
Direct all constraints washington 233 customer	NUMBER					
	SIGNATURE OF ATTORNEY					
Name <u>Di</u>	on R. Ferguson Re	gistratio	on No 59,561			
Signature _	/Dion R. Ferguson/ Da	ate Se	ptember 5, 2008			